

**AMENDMENTS TO THE ABSTRACT**

Please replace the Abstract with the following:

A manufacturing method of ceramic device including the steps of forming a piezoelectric/electrostrictive layer on said metal substrate using a mixture of photosensitive resin and piezoelectric/electrostrictive ceramic, masking and exposing said piezoelectric/electrostrictive layer to pattern the piezoelectric/electrostrictive layer, forming an upper electrode on said piezoelectric/electrostrictive layer using a mixture of photosensitive resin and metal and masking and exposing said upper electrode to pattern it.